Hiroaki INOUE et al.

In re application of

Attn: BOX PCT

Serial No. NEW

Docket No. 2001\_1094A

Filed August 1, 2001

ELECTROLESS PLATING LIQUID AND METHOD OF FORMING INTERCONNECTION USING SUCH AN ELECTROLESS PLATING LIQUID [Corresponding to PCT/JP00/09099 Filed December 21, 2000]

## **PRELIMINARY AMENDMENT**

Assistant Commissioner for Patents, Washington, DC 20231

Sir:

<u>Prior to calculating the filing fee</u>, please amend the above-identified application as follows:

## IN THE SPECIFICATION

Page 1, immediately after the title, please insert:

This application is a 371 of PCT/JP00/09099 filed December 21, 2000.

## IN THE CLAIMS

Please amend claim 5 as follows:

(Amended) A method of forming a copper interconnection on a semiconductor device, characterized by the steps of forming an auxiliary seed layer for reinforcing a copper seed layer in an interconnection groove defined in a surface of the semiconductor device using an electroless copper plating liquid containing dihydric copper ions, a complexing agent, and an aldehyde acid, and performing an electrolytic plating process using the seed layer including said auxiliary seed